

I | MOSFET

①

Metals-Oxide-Semiconductor-Field-Effect-Transistor

- Most widely used semiconductor devices

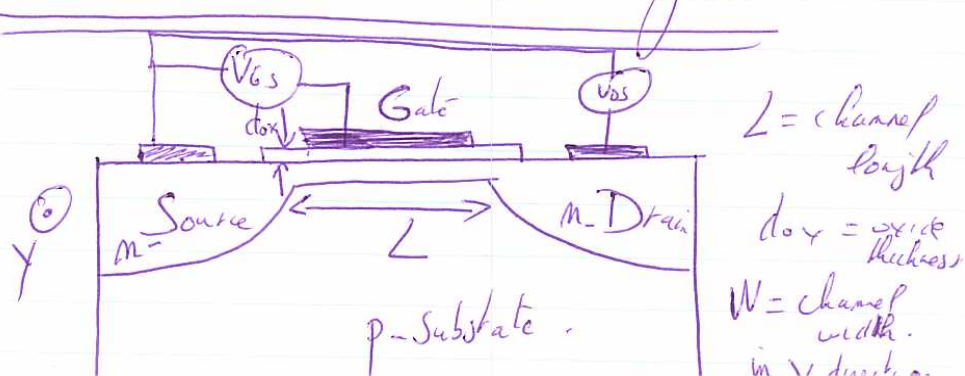
[Figure 7.1 of textbook \rightarrow Moore's law: exponential growth of integration density with time.]

- 2 types of MOSFET
 - \rightarrow n-channel MOSFET or nFET
 - \rightarrow p-channel MOSFET or pFET

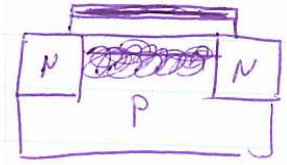
[The most commonly used technology is CMOS (Complementary MOS) in which both n-channel and p-channel transistors are fabricated.]

- we limit here our analysis to nFET where ~~the~~ ~~most~~ ~~responsible~~ the current flow is due to e^- .

① Introduction to MOSFET operation



* Transistor is "off" state

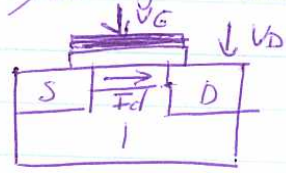


operation principle

* Applying a voltage V_G to the gate "inverts" the channel region creating an electrical path between the source and drain.



* Applying a voltage to the Drain pulls current - causes across the channel, creating the drive current (I_D)



* The role of gate electrode for n-channel MOSFET

Positive gate voltage does two things-

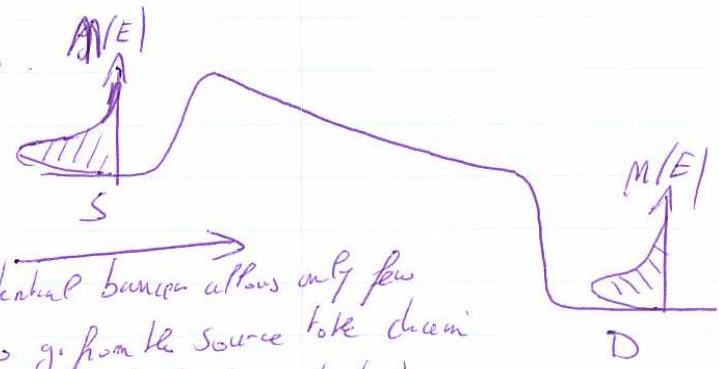
(1) Reduces the potential energy barrier seen by the e^- from the source and the drain regions



(2) Inverts the surface, and increases the conductivity of the channel.

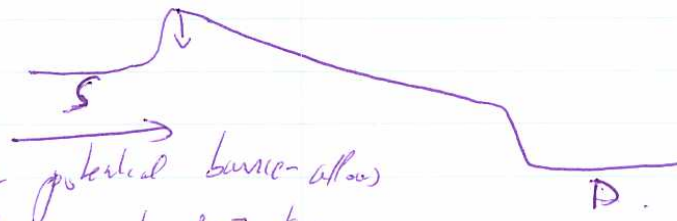
* The role of the Drain electrode for n-channel MOSFET

$V_G = 0, V_D > 0$



Large potential barrier allows only few e^- to go from the source to the drain (subthreshold conduction).

$V_G > 0, V_D > 0$

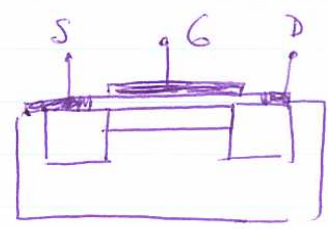


Smaller potential barrier allows a large number of e^- to go from the source to the drain.

* Qualitative description of MOSFET operation

(a) $V_G > V_T, V_D > 0$ (small)

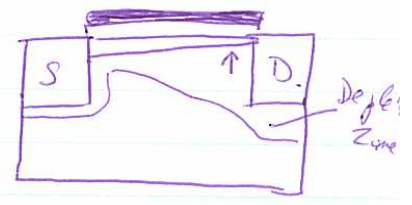
Variation of e^- density along the channel is small



$I_D \propto V_D \Rightarrow$ linear regime

(b) $V_G > V_T, V_D > 0$ (large-1)

Increase in the drain current reduce due to the reduced conductivity of the channel at the drain end

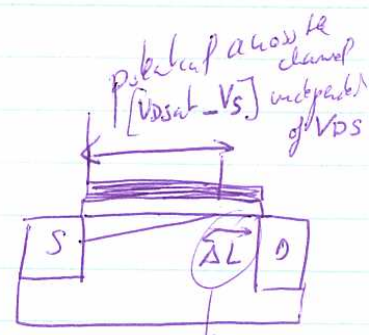


(c) $V_G > V_T, V_D = V_{DSat}$
 Draw saturation voltage.

Punch-off point: e^- density at the end channel is identically zero.

(d) $V_G > V_T; V_D > V_{DSat}$

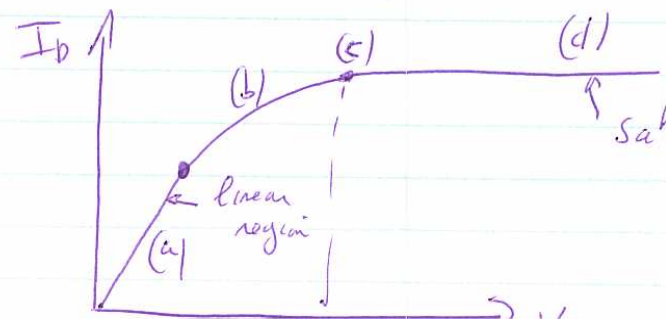
Post punch-off characteristics. The excess drain voltage is dropped across the highly resistive punch-off region denoted by ΔL



high electric field \Rightarrow drift of carriers.

\Rightarrow current saturates since it's fixed by the potential dropped across the channel. Saturation region.

\Rightarrow



② MOSFET analysis

⑤

① The linear Model

It describes the behavior of a MOSFET biased with a small drain-to-source voltage -
* MOSFET acts as a linear device \Rightarrow can be modeled as a linear resistor whose resistance is modulated by the gate voltage -

General expression for the Drain current.

$$I_D = - \frac{Q_{inv} W L}{t_r}$$

Q_{inv} = inversion layer charge per unit of area -

W = gate width

L = gate length.

t_r = transit time

$$t_r = \frac{L}{v} \quad v = \text{velocity}$$

$$v = \mu E = \mu \frac{V_{DS}}{L}$$

mobility electric field

$$\Rightarrow I_D = - \mu Q_{inv} \frac{W}{L} V_{DS}$$

we saw that (MOS capacitor) $V_G = V_T - \frac{Q_{inv}}{C_{ox}}$

$\Rightarrow Q_{inv} = -C_{ox} (V_G - V_T)$ if $V_G > V_T$

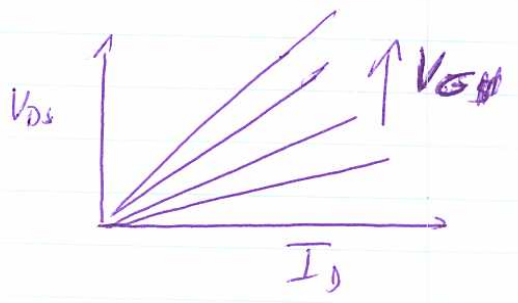
with $V_T = V_{FB} + V_S + \frac{2\epsilon_0 q N_A V_S}{C_{ox}}$ $V_S = 2V_F$

So $I_D = \mu C_{ox} \frac{W}{L} (V_G - V_T) V_{DS}$

for $|V_{DS}| \ll (V_G - V_T)$

x Also $I_D = 0$ if $V_G < V_T$.

x $|V_{DS}| \ll (V_G - V_T) \Rightarrow$ means that n, E, Q_{inv} is constant between source and drain.



⑤ The quadratic model

The model ^{for the charge} includes the voltage variation between source and drain - the variation of the depletion layer charge is ignored, not the variation of the inversion layer charge - it is the most commonly used model.

The charge on the gate is completely balanced by $Q_{ch}(x)$ ⑦
 $Q_{ch}(x) \approx -C_{ox}(V_G - V_T - V(x))$
 We consider a small section with width dy ,
 and channel voltage V_c .

~~$V_{DS} \Rightarrow V_G - V_c$ used to find I_D . Since $V_G \rightarrow V_{DS}$~~

So the previous expression from the linear model becomes

$$I_D = \mu C_{ox} \frac{W}{dy} (V_G - V_c - V_T) dV_c$$

where $\begin{cases} L \rightarrow dy & \text{locally} \\ V_{DS} \rightarrow dV_c \end{cases}$

integrating from
Source to Drain.

$$\int_0^L I_D dy = \mu C_{ox} W \int_0^{V_{DS}} (V_G - V_c - V_T) dV_c$$

I_D is constant along the channel so \Rightarrow

$$I_D = \mu C_{ox} \frac{W}{L} \left[(V_G - V_T)V_{DS} - \frac{V_{DS}^2}{2} \right] \quad (*)$$

The Drain current just increases linearly with the applied drain to source voltage, but then reaches a maximum value. $V_{DS} < V_G - V_T$

$$y \left[V_{DS} = V_G - V_T \right] \Rightarrow \left. \frac{dI_D}{dV_{DS}} = 0 \right|_{V_{DS} = V_G - V_T}$$

Drain saturation voltage $V_{DS,sat}$

We call $I_{D, SAT}$, the value of the saturated drain current. \Rightarrow pinch-off point.

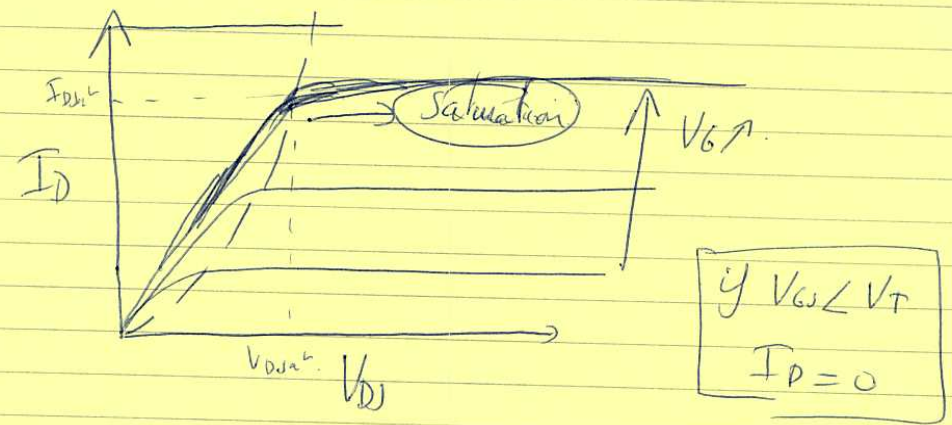
$$\Rightarrow I_{D, SAT} = \mu C_{ox} \frac{W}{L} \frac{(V_{GS} - V_T)^2}{2}$$

$Q_{inv} = 0$ at the drain voltage

The equation (*) is not valid beyond the pinch-off point

if $V_{DS} > V_{GS} - V_T \Rightarrow$ the current maintains the value $I_{D, SAT}$.

The gradual channel model explains the typical I-V characteristics of a MOSFET, which are normally plotted for different V_{GS} .



* We would like to calculate the transconductance g_m and
 (i) the ~~output~~ transconductance g_m is given by

$$g_m = \left. \frac{\partial I_D}{\partial V_{GS}} \right|_{V_{DS} \text{ etc}} \quad \left(\text{if } g_m \nearrow \text{ speed of the device } \nearrow \right)$$

Here we get $g_{m, \text{quad}} = \mu C_{ox} \frac{W}{L} V_{GS}$ if $V_{GS} < V_{GS} - V_T$
 in the quadratic region

In saturation $g_{m, \text{sat}} = \mu C_{ox} \frac{W}{L} (V_{GS} - V_T)$

(ii) the output conductance g_d is given by

$$g_d = \left. \frac{\partial I_D}{\partial V_{DS}} \right|_{V_{GS}} \quad \left[\begin{array}{l} \text{"ease of work which an electric} \\ \text{current flows through a material"} \\ \rightarrow \text{reciprocal of resistance} \end{array} \right]$$

$$g_d = \frac{\mu C_{ox} W}{L} (V_{GS} - V_T - V_{DS}) \quad \left[\text{in the quadratic region} \right]$$

$g_d \searrow \quad \nearrow V_{DS}$

and $g_d \rightarrow 0$ as the device operated in the saturated region

$$g_{d, \text{sat}} = 0$$

(c) The variable depletion layer model

includes now the variation of the charge in the depletion layer between source and drain.

$$Q_{inv} = -C_{ox} (V_{GS} - V_T) V_{DS} > V_T$$

however now we include the implicit dependence of V_T on the charge in the depletion layer.

$$V_T = V_{FB} + V_S + \frac{\sqrt{2\epsilon q N_A V_S}}{C_{ox}} \quad \boxed{V_S = 2V_F + V_C}$$

$$\Rightarrow \left[V_T = V_{FB} + 2V_F + V_C + \frac{\sqrt{2\epsilon q N_A (2V_F + V_C)}}{C_{ox}} \right]$$

The voltage V_C is the difference channel voltage $V_C(y)$

$$\Rightarrow I_D = \mu C_{ox} \frac{W}{L} \int_0^L (V_{GS} - V_{FB} - 2V_F - V_C(y) - \frac{\sqrt{2\epsilon q N_A (2V_F + V_C(y))}}{C_{ox}}) V_{DS} dy$$

y varies from 0 to L . $V_C(y)$ varies from 0 to V_{DS}

$$\left(I_D = \mu C_{ox} \frac{W}{L} (V_{GS} - V_{FB} - 2V_F - \frac{V_{DS}}{2}) V_{DS} - \frac{2}{3} \mu \frac{W}{L} \sqrt{2\epsilon q N_A} \left[(2V_F + V_{DS})^{3/2} - (2V_F)^{3/2} \right] \right)$$

an integration from V_s to V_D

$$I_D = \mu C_{ox} \frac{W}{L} \left\{ \left(V_G - V_{FB} - 2V_F - V_S - \frac{V_{Dj}}{2} \right) V_{DS} - \frac{2}{3} \gamma \left[(2V_F + V_D)^{3/2} - (2V_F + V_S)^{3/2} \right] \right\}$$

$$\gamma = \sqrt{\frac{2q\epsilon_s N_a}{C_{ox}}}$$

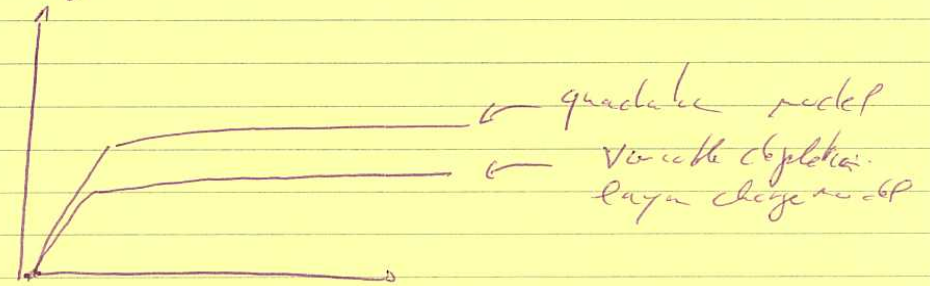
Again this expression is not valid after the pinch-off point for describing the saturation region.

The drain voltage at which saturation occurs can be

$V_{D,sat} = V_D$ found setting $\frac{dI_D}{dV_D} = 0$.

$$\Rightarrow V_{D,sat} = V_G - V_{FB} - 2V_F + \frac{\gamma^2}{2} - \gamma \sqrt{\frac{V_G - V_{FB} + \gamma^2}{4}}$$

Actually the quadratic model yields to larger current compared to the more accurate derivation.



it can fall transconductance.

~~$g_{m, sat} = \mu C_{ox} \frac{W}{L} (V_G - V_{th})$~~

$g_{m, sat} = \mu C_{ox} \frac{W}{L} V_{D0}$ (still)

and $g_{m, sat} = \mu C_{ox} \frac{W}{L} V_{D, sat}$ \Rightarrow almost linear with V_G

so it can be also written

$g_{m, sat} = \mu^* C_{ox} \frac{W}{L} (V_G - V_{th})$ with modified μ^*

$\mu^* = \mu \left[1 - \frac{1}{\sqrt{1 + \frac{2(V_{th} + V_G) C_{ox}^2}{q N_a \epsilon_{si}}}} \right]$

(d) Influence of substrate bias on threshold voltage

We saw that $V_T = V_{FB} + 2V_F + \gamma \sqrt{2V_F}$

$$\gamma = \frac{\sqrt{2q\epsilon_{si}N_A}}{C_{ox}}$$

where we supposed that both the source and the substrate were grounded. $V_S - V_{sub} = 0$.

In many applications, the source and the substrate may be at different potential.

The depletion charge under the channel is obtained by:

$$Q_d(y) = -\sqrt{2q\epsilon_{si}N_A(2V_F + V_c(y) - V_{sub})} \quad V_{sub} < 0$$

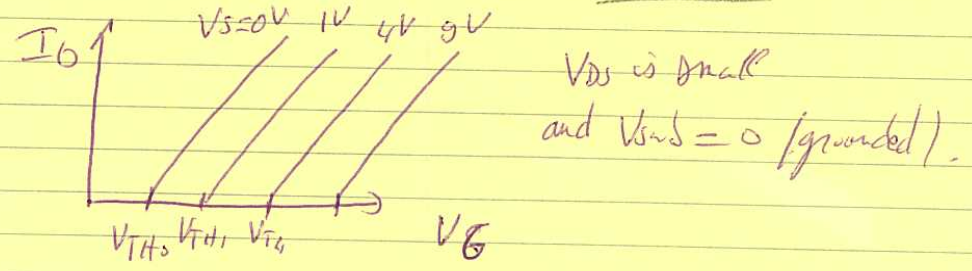
$$V_T = V_{FB} + 2V_F + V_c(y) + \gamma \sqrt{2V_F + V_c(y) - V_{sub}}$$

$$\text{at } y=0 \Rightarrow V_c(y) = V_S$$

$$y \quad (i) \quad V_{sub} = 0; \quad V_S > 0 \Rightarrow V_{TH} = V_S + V_{FB} + 2V_F + \gamma \sqrt{2V_F + V_S}$$

$$(ii) \quad V_{sub} < 0; \quad V_S = 0 \Rightarrow V_{TH} = V_{FB} + 2V_F + \gamma \sqrt{2V_F - V_{sub}}$$

In conclusion, V_T increases as a function of the potential difference between source and ~~drain~~ substrate.



③ Surface mobility

The mobility μ_m that we used is the one associated with the "surface mobility". surface mobility is lower than ~~sub~~ bulk mobility. because of scattering at the silicon-oxide interface.

The surface mobility depends on how much e^- interact at the interface, and therefore it depends on the vertical ~~the~~ electrical field, which 'pushes' e^- against the interface.
~~with~~ if $E = 0$ we ~~use~~ denote $\mu_m \equiv \mu_{no}$.

The current in the transistor is given by

$$I_D = \frac{W}{L} \int_{V_S}^{V_D} \mu_m (-Q_{inv}(y)) d(y)$$

constant μ_m and the electric

There exists an empirical relationship that describes the dependence of surface mobility on vertical electric field in the channel, E_x .

$$\mu_n(y) = \frac{\mu_{n0}}{1 + \theta E_x(y)} \quad \theta = \text{mobility reduction factor}$$

The average electric field in the channel is given by

$$E_x(y) = \frac{E_o(y) + E_{si}(y)}{2} \quad E_{so} = \text{electric field at the silicon-oxide interface}$$

According to Gauss Law

E_{si} = electric field at the boundary between inversion layer and depletion region

(i) $E_{si} E_{so}(y) = \epsilon_x E_{ox}(y) \quad E_{ox} = \frac{V_G - V_{FB} - V_{si}(y)}{d_{ox}}$
 $\Rightarrow E_{si} E_o(y) = C_{ox} [V_G - V_{FB} - V_{si}(y)] = - [Q_{inv}(y) + Q_d(y)] = -Q_E(y)$

(ii) $E_{si} E_{si}(y) = -Q_d(y) = -\gamma C_{ox} \sqrt{V_{si}(y)}$

$$\Rightarrow E_x(y) = \frac{C_{ox}}{2 \epsilon_{si}} (V_G - V_{FB} - V_{si}(y) + \gamma \sqrt{V_{si}(y)})$$

$$\Rightarrow \mu_m(y) = \frac{\mu_{n0}}{1 + \frac{C_{ox}}{2\epsilon_{si}} (V_G - V_{FB} - V_{ds}(y) + \delta \sqrt{V_{ds}(y)})}$$

We want to simplify the calculation of the Drain current.

I_D calculated with $\mu_m(y)$ depending on $E_x(y) \equiv I_D$ calculated with a μ_{eff}

• Let us consider a small element dy .

$$\Rightarrow I_D dy = W \mu_{eff} (-Q_{in}(y)) dV(y)$$

$$\Rightarrow I_D \cdot dy = \frac{W \mu_{n0} (-Q_{in}(y)) dV(y)}{1 + \frac{C_{ox}}{2\epsilon_{si}} (V_G - V_{FB} - V_{ds}(y) + \delta \sqrt{V_{ds}(y)})}$$

we substitute and integrate from source to drain.

$$\left[\int_0^L \left\{ 1 + \frac{C_{ox}}{2\epsilon_{si}} (V_G - V_{FB} - V_{ds}(y) + \delta \sqrt{V_{ds}(y)}) \right\} dy \right] = L \frac{\mu_{n0}}{\mu_{eff}} \quad (*)$$

Remark $V_{ds}(y) = 2V_F + V_c(y)$

$$\frac{dV}{dy} \approx \frac{V_D - V_S}{L} \text{ (linear approximation)}$$

we can write the following identity:

$$\int_0^L \left[\frac{V(y)}{y} - \gamma \sqrt{2V_F + V(y)} \right] dy = \frac{L}{V_D - V_S} \int_{V_S}^{V_D} \left[\frac{V(y)}{y} - \gamma \sqrt{2V_F + V(y)} \right] dV$$

$$= \frac{L}{V_D - V_S} \left[\frac{V_D^2 - V_S^2}{2} - \frac{2\gamma}{3} \left\{ (2V_F + V_D)^{3/2} - (2V_F + V_S)^{3/2} \right\} \right]$$

introducing in (*), we get (after calculation):

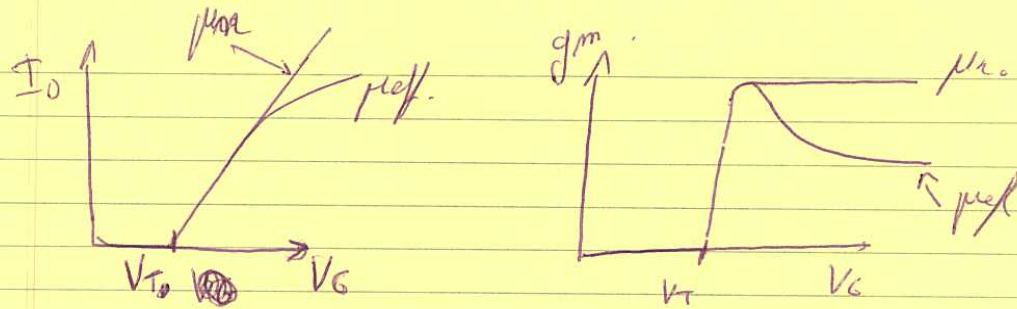
$$\frac{\mu_{no}}{\mu_{eff}} = 1 + \frac{\alpha C_{ox}}{2\epsilon_{si}} \left[V_G - V_T + \gamma \sqrt{2V_F} - \frac{V_S + V_D}{2} + \frac{2\gamma}{3} \frac{(2V_F + V_S)^{3/2} - (2V_F + V_D)^{3/2}}{V_D - V_S} \right]$$

$$\Rightarrow \left[\mu_{eff} = \frac{\mu_{no}}{1 + \frac{\alpha C_{ox}}{2\epsilon_{si}} (V_G - V_T - V_S + 2\gamma \sqrt{2V_F + V_S})} \right]$$

~~Assuming~~ Neglecting the influence of depletion charge near the source; after simplification and also

with $\alpha = \frac{\alpha C_{ox}}{2\epsilon_{si}}$

$$\Rightarrow \left[\mu_{eff} = \frac{\mu_{no}}{1 + \alpha (V_G - V_T - V_S)} \right]$$



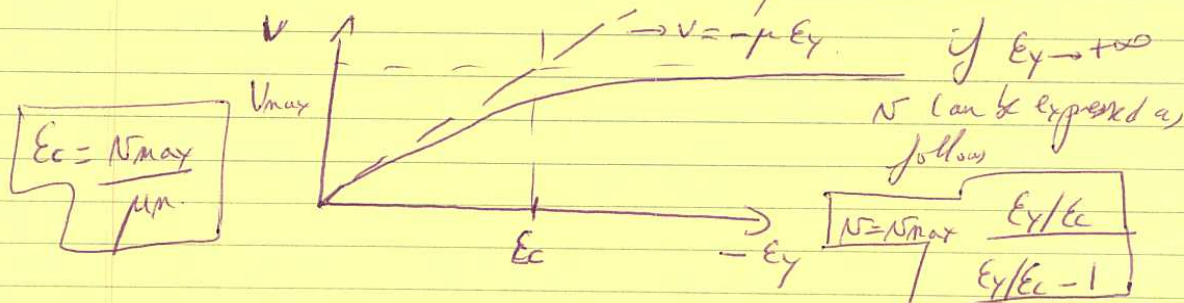
④ Carrier velocity saturation

So far we consider a linear dependency of the drift current on the lateral electric field. $\rightarrow y$

$[q \mu_n n E_y = -q v n]$ $v =$ velocity of carrier in the inversion layer

Actually, this is wrong for low electric field only. At high electric field, and above a critical value, the carrier velocity saturates.

$\underline{ex} = e^-$ in silicon, max velocity is 10^7 cm/s



What is the impact of the velocity saturation effect on the expression of the drain current of a MOSFET.

if $V_0 \geq V_{sat}$ E_y reaches high value near the drain junction.
the drain current:

$$I_D = -W Q_{in}(y) \mu_n \frac{dV(y)}{dy} = W Q_{in} \mu_n E_y$$

if $E_y \rightarrow \infty$ then $Q_{in}(y) \rightarrow 0$.

from $v = v_{max} \frac{E_y / E_c}{E_y / E_c + 1}$ and using $\begin{cases} E_c = v_{max} / \mu_n \\ E_y = -dV(y)/dy \end{cases}$

$$\Rightarrow v(y) = v_{max} \frac{-\frac{1}{E_c} \frac{dV(y)}{dy}}{-\frac{1}{E_c} \frac{dV(y)}{dy} + 1} = \mu_n \frac{\frac{dV(y)}{dy}}{1 + \frac{1}{E_c} \frac{dV(y)}{dy}}$$

The expression of the current becomes:

$$I_D = -W \left(\frac{\mu_n}{1 + \frac{1}{E_c} \frac{dV(y)}{dy}} \right) Q_{in}(y) \frac{dV(y)}{dy}$$

just replace $\mu_n \rightarrow \frac{\mu_n}{1 + \frac{1}{E_c} \frac{dV(y)}{dy}}$ to account for velocity saturation

integrating from source to Drain yields.

$$I_D = \frac{W}{L} \left(\frac{\mu_n}{1 + \frac{V_{DS}}{E_c}} \right) \int_{V_S}^{V_D} Q_{inv}(y) dV(y).$$

$$\Rightarrow I_D = \frac{W}{L} \left(\frac{\mu_n}{1 + \frac{V_{DS}}{E_c}} \right) C_{ox} \left[(V_G - V_T)V_{DS} - \frac{V_{DS}^2}{2} \right]$$

↑
using
quadratic
model

by imposing $\frac{dI_D}{dV_{DS}} = 0 \Rightarrow$ drain saturation voltage is

$$V_{D\ sat} = L E_c \left[\sqrt{1 + \frac{2(V_G - V_T)}{L E_c}} - 1 \right]$$

when velocity saturation is taken into account this is equivalent to making the channel longer L is multiply

$$\text{by } \left(\frac{1 + \frac{V_{DS}}{E_c}}{L E_c} \right)$$

Therefore \Rightarrow the Drain saturation voltage and the drain saturation current are reduced.

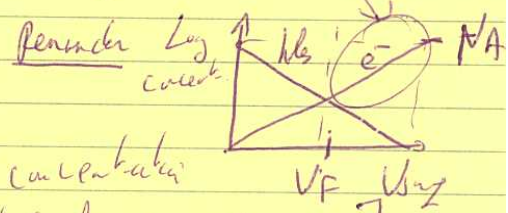
(5) Subthreshold current characteristics.

(a) Subthreshold current

So far we assumed that $I_D = 0$ if $V_G \ll V_T$

Actually there is a significant amount of e^- near the surface if the device operates at below strong inversion.

$V_F < V_{inj} < 2V_F$



[The actual dependence of the e^- concentration at the surface is an exponential function of V_{surf}]

⇒ Experimentally we have that the Drain current below threshold "subthreshold current" is independent of the drain voltage. ⇒ This means that the subthreshold current is caused by diffusion rather than drift mechanism.

current density from source to Drain can be written

$$J_{ny} = -qD \frac{dn}{dy} \Rightarrow I_D = qA D n \frac{m(1-\eta)}{L}$$

As the cross-sectional area of the channel region.

e^- density at the ~~center~~ edge of same width =

$$n(x) = n_{p0} \exp\left(\frac{qV_{surf}}{k_B T}\right) \quad n(L) = n_{p0} \exp\left(\frac{q(V_{surf} - V_b)}{k_B T}\right)$$

$$Mq_0 = \frac{M_L^2}{N_A}$$

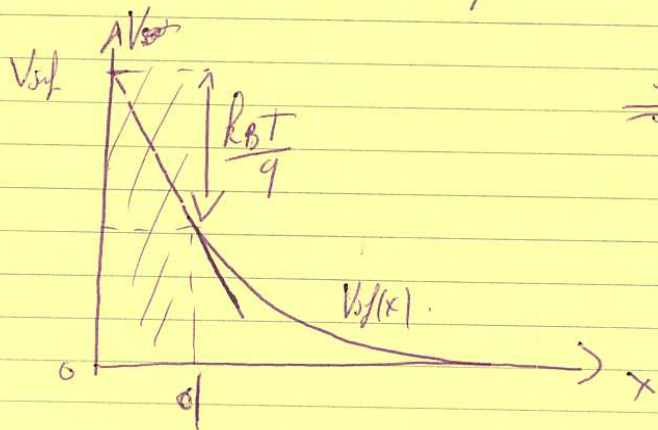
(→ source is considered here at ground).

what is the area A?

we know that the e^- density varies as $\exp\left(\frac{qV_{surf}}{k_B T}\right)$ near the surface - we however going to

approximate the exp-profile by a constant e^- density extending to a depth d below the surface.

The depth d is defined as the depth at which the potential has decreased by $k_B T / q$. Below the surface potential value



⇒ so $A = W \times d$

W (width of the transistor)

$$d = \frac{k_B T / q}{E_s} \quad E_s = -\frac{dV(x)}{dx} \Big|_0$$

Using the ~~modified~~ Einstein relationship $\mu_n \frac{k_B T}{q} = D_n$

we get the saturation current

$$I_D = \mu_n \frac{W}{L} q \left(\frac{k_B T}{q} \right) \frac{n_i^2}{N_A} \left[1 - \exp(-qV_D/k_B T) \right] \times \frac{\exp(qV_{bi}/k_B T)}{-\frac{dV_{bi}}{dx}}$$

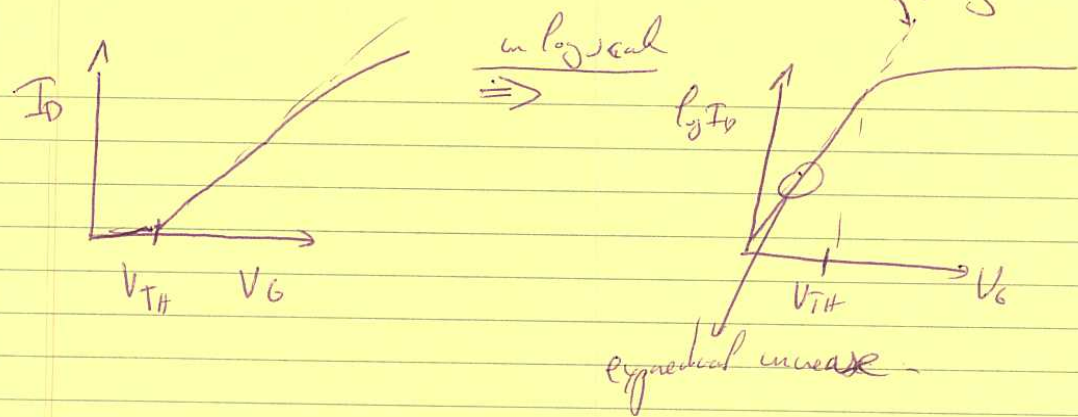
The electric field at the surface E_s is given by

(Max capacitor relation) $-\frac{dV_{bi}}{dx} \Big|_{x=0} = E_s = \sqrt{\frac{2q N_A V_{bi}}{\epsilon_s}}$

$$\Rightarrow E_s = \frac{q N_A}{C_D}$$

$\Rightarrow I_D$ is independent of V_D as long as V_D is larger than a few $\frac{k_B T}{q}$. (exponential term $\rightarrow 0$)

$\Rightarrow I_D$ also increases exp. with the surface potential.



Subthreshold slope

it is $\frac{1}{S}$ (inverse of the slope) \Rightarrow $S = \frac{dV_G}{d \log(I_D)}$

\Rightarrow represents how many millivolts per decade.

\Rightarrow "how many millivolts V_G be increased to increase I_D by a factor 10"

(↓ S ↓) efficiency and switching speed of the device from off-state to on-state ↑

$$S = \frac{\ln(10)}{\frac{d(\ln(I_D))}{dV_G}} \quad \log_{10} \rightarrow \log_e \equiv \ln$$

$$Ab_0 \quad \frac{d \ln(I_D)}{dV_G} = \frac{d(\ln I_D)}{dV_G} \cdot \frac{dV_G}{dV_G}$$

$$\frac{d \ln(I_0)}{dV_{\text{surf}}} = \frac{d}{dV_{\text{surf}}} \left[\ln \left(e^{\frac{qV_{\text{surf}}}{k_B T}} \right) - \ln \left(\frac{dV_{\text{surf}}}{dx} \right) \right]$$

$$= \left[\frac{q}{k_B T} - \frac{\frac{d}{dV_{\text{surf}}} \left(-\frac{dV_{\text{surf}}}{dx} \right)}{-\frac{dV_{\text{surf}}}{dx}} \right] \quad (*)$$

$$\frac{d}{dV_{\text{surf}}} \left(-\frac{dV_{\text{surf}}}{dx} \right) = \frac{C_D}{\epsilon_{\text{sc}}} \quad (\text{from Poisson})$$

C_D is the depletion capacitance $\left[C_D = -\frac{dQ_d}{dV_{\text{surf}}} \right] = \frac{\epsilon_{\text{sc}}}{2d}$

$$\Rightarrow \frac{\frac{d}{dV_{\text{surf}}} \left(-\frac{dV_{\text{surf}}}{dx} \right)}{-\frac{dV_{\text{surf}}}{dx}} = \frac{C_D^2}{q N_A \epsilon_{\text{sc}}} = \frac{1}{2V_{\text{surf}}}$$

in weak inversion regime $V_F < V_{\text{surf}} < 2V_F$,

$\frac{1}{2V_{\text{surf}}}$ is small compared to $\frac{q}{k_B T} \Rightarrow$ it was neglected in (*)

$$\frac{d \ln(I_0)}{dV_G} \approx \frac{q}{k_B T} \frac{dV_{\text{surf}}}{dV_G}$$

Also $V_G = V_{FB} + V_{surf} - \frac{Q_d}{C_{ox}}$

$\Rightarrow \frac{dV_{surf}}{dV_G} = \left(1 + \frac{C_D}{C_{ox}}\right)^{-1}$ [do $\frac{dV_G}{dV_{surf}}$ first]

\Rightarrow finally

$S = \frac{k_B T}{q} \ln(10) \left(1 + \frac{C_D}{C_{ox}}\right)$

$\left(\frac{1 + C_D}{C_{ox}}\right) = m$
body factor

Ab. since $\frac{d(\ln I_D)}{dV_G} = \frac{q}{k_B T m}$

$\Rightarrow I_D \sim \exp\left(\frac{q V_G}{m k_B T}\right)$

The subthreshold current varies exponentially as a function of the gate voltage.

* In case where we consider interface

states (or traps) in the Si energy bandgap at the silicon

oxide interface. one can ~~define~~ associate

~~Q_{it}~~ a charge of these interface state Q_{it} .

$\Rightarrow C_{it} = \frac{-dQ_{it}}{dV_{surf}}$

we get after calculations,

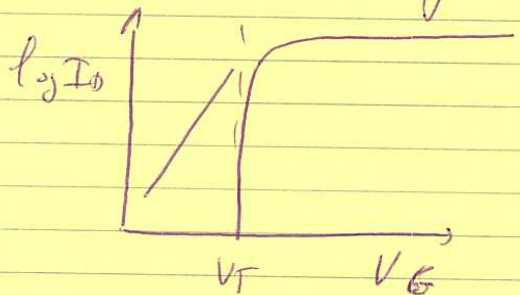
$$S = \frac{k_B T}{q} \ln(10) \left(1 + \frac{C_D + C_L}{C_{ox}} \right)$$

$$= 60 \left(1 + \frac{C_D + C_L}{C_{ox}} \right) \text{ at room temperature}$$

mV/decade -

6) Continuous model

The model developed so far for $V_G > V_T$
 or for $V_G < V_T$ do not connect well around
 $V_G = V_T$ (discontinuity). Since often V_G is
 close to V_T , this is a problem.



A model which is valid everywhere can be derived.

Indeed,
$$I_D = \mu_m C_{ox} \frac{W}{L} \int_{V_S}^{V_D} - \frac{Q_{inv}(y)}{C_{ox}} dV(y)$$

can be rewritten

$$I_D = \mu_m C_{ox} \frac{W}{L} \left\{ \int_{V_S}^{V_P} - \frac{Q_{inv}(y)}{C_{ox}} dV(y) - \int_{V_P}^{V_D} - \frac{Q_{inv}(y)}{C_{ox}} dV(y) \right\}$$

$V_P = (V_G - V_T) \equiv$ channel saturation voltage if source is grounded and $V_G > V_T$

$$I_D = I_F - I_R$$

forward current reverse current

It is possible to find a potential function which describes the evolution of the current as a function of gate and drain voltage for all regime of operation (depletion, weak and strong inversion)

⇒ Emz, Krummenacker, Vittoz

⇒ EKV Model

$$I_D = 2\mu_m C_{ox} \frac{W}{L} \left(\frac{k_B T}{q} \right)^2 \left\{ \frac{1}{4} \left[\ln \left(1 + \exp \left(\frac{V_P - V_S}{2 \frac{k_B T}{q}} \right) \right) \right]^2 - \left[\ln \left(1 + \exp \left(\frac{V_P - V_D}{2 \frac{k_B T}{q}} \right) \right) \right]^2 \right\}$$

For example:

if $V_s = 0$, $V_p < V_p$ $V_G > V_T \Rightarrow$ the transistor operates in non-saturated regime.

\Rightarrow exponential terms $\gg 1$

$$I_D = 2 \mu_n C_{ox} \frac{W}{L} \left[\frac{k_B T}{q} \right]^2 \left[\left(\frac{V_p}{2 k_B T / q} \right)^2 - \left(\frac{V_p - V_D}{2 k_B T / q} \right)^2 \right]$$

$$= \frac{1}{2} \mu_n C_{ox} \frac{W}{L} [2 V_D V_p - V_D^2]$$

\Rightarrow quadratic model

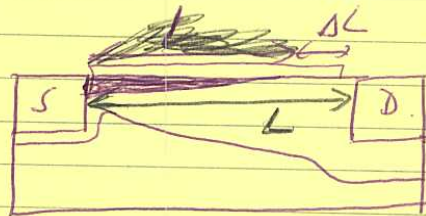
$$I_D = \frac{1}{2} \mu_n C_{ox} \frac{W}{L} \left[(V_G - V_T) V_D - \frac{V_D^2}{2} \right]$$

⑦ Channel length modulation

Previously we assumed that when $V_D > V_{Dsat}$, the Drain current of a MOSFET is constant and equal to I_{Dsat} .

Actually if $V_D >$ beyond V_{Dsat} , the depletion ~~cap.~~ region and local threshold voltage near the Drain are increased

The effective length of the channel is $L - \Delta L$
(~~is~~ ~~dependent~~ ~~of~~ ~~region~~)



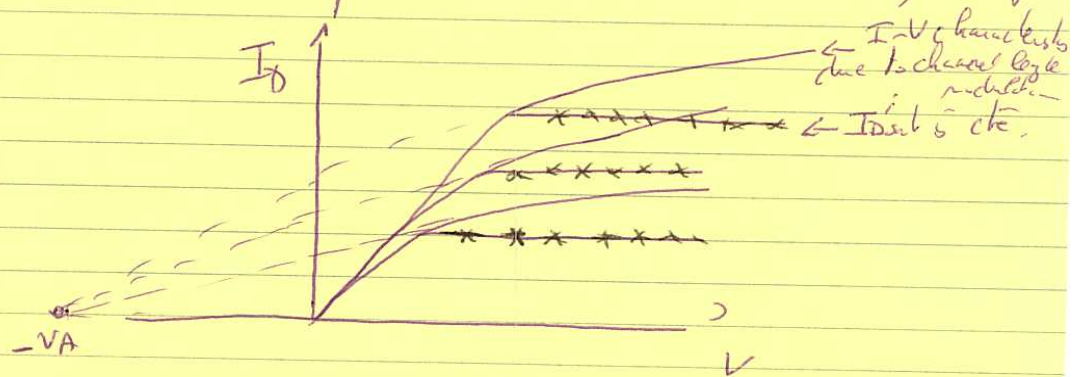
and shorter channel length \Rightarrow increase in Drain current.

if I_{Dsat} is ~~the saturation~~ is obtained if $(V_D = V_{Dsat})$

if $V_D > V_{Dsat}$

$$I_{Dsat}' = I_{Dsat} \left(1 + \frac{V_D - V_{Dsat}}{V_A + V_{Dsat}} \right)$$

where V_A is a positive voltage value that can be obtained experimentally. V_A is called "early voltage"



in term of channel length modulation, we get

$$\frac{I_{Dsat}L}{L} = \frac{I_{Dsat}}{L - \Delta L}$$

$$\Rightarrow \Delta L = L \left[1 - \frac{1}{1 + \frac{V_D - V_{Dsat}}{V_A + V_{Dsat}}} \right]$$

The saturation output ~~current~~ conductance, which was previously considered equal to zero, is now given by:

$$g_{Dsat} = \frac{dI_{Dsat}}{dV_D} = \frac{I_{Dsat}}{V_A + V_{Dsat}} \approx \frac{I_{Dsat}}{V_A}$$

- * The channel length modulation effect typically increases in small devices with low-doped substrates.
- * Finger scaling can reduce the channel length modulation by increasing the finger density (as the gate length is reduced)

⑧ Short-channel effect

evolution of semiconductor processing technology enables scaling of transistors.

Ex gate length of MOSFET used in 256K DRAM in 1984

was $\approx 1.2 \mu\text{m}$.

in 1994, 64 M DRAM were produced using $0.4 \mu\text{m}$

prediction 50nm in 2009
35nm in 2012.

~~aggressive~~ aggressive scaling \Rightarrow undesirable effects including the short-channel effect.

[Here the depletion layer widths of the source and drain junction become comparable to the channel length.

Let us look at the threshold $V_T = V_{FB} + 2V_F - \frac{Q_d}{C_{ox}}$

where Q_d can be represented by a trapezoidal area.

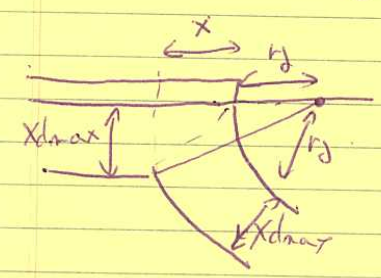


Area of the trapezoid is $\frac{(L+L_1)x_{dmax}}{2}$.

- if the channel is long $L \approx L_1 \Rightarrow$ area $\approx L x_{dmax}$ (Rectangular area)
 It is then accurately described by the equation derived previously.
- if the channel (gate) is short $L_1 \ll L$, then the depletion charge due to V_G under the gate electrode is reduced.

Consider that $V_G = V_T$ and $V_{DS} \approx 0$.

Based on geometrical consideration we get:



$$x^2 + (x+r_j)^2 = (r_j + x_{dmax})^2$$

Here we suppose also that the built-in potential of the source and drain junction is approximately equal to $2V_T$
 \Rightarrow width of the depletion region around source and drain is then $\approx x_{dmax}$

$$\Rightarrow x^2 + 2r_j x - 2r_j x_{dmax} = 0$$

where $x = -r_j \pm \sqrt{r_j^2 + 2r_j x_{dmax}} = r_j \left(\frac{-1 \pm \sqrt{1 + 2x_{dmax}/r_j}}{1} \right)$

$\Rightarrow x$ must be positive. So

L_1 then is given by

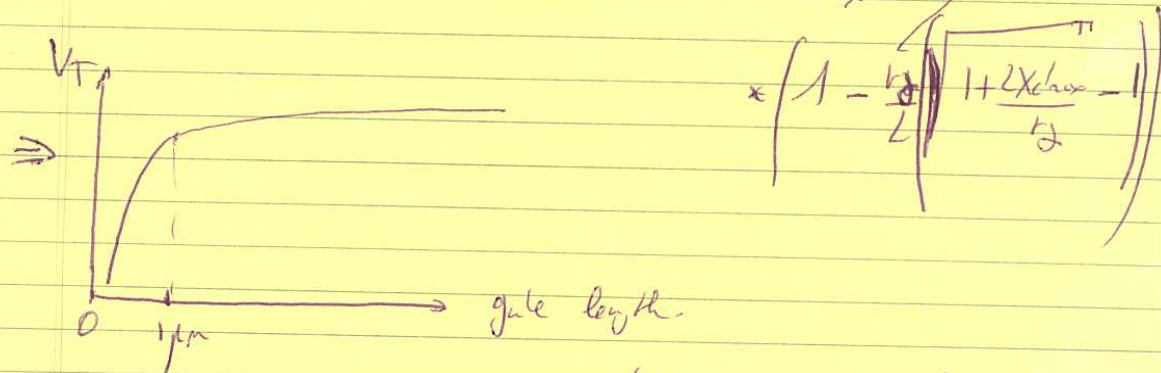
$$L_1 = L - 2x = L - 2r_j \left(\sqrt{1 + \frac{2x_{dmax}}{r_j}} - 1 \right)$$

The depletion charge controlled by the gate voltage is

$$Q_d = -q x_{dmax} N_A \left(\frac{L + L_1}{2} \right) \\ = -q x_{dmax} N_A L \left(1 - \frac{r_j}{L} \left(\sqrt{1 + \frac{2x_{dmax}}{r_j}} - 1 \right) \right)$$

$\Rightarrow Q_{d0}$ which is the depletion charge if the depletion region would be considered rectangular.

$$V_T = V_{FB} + 2V_P - \frac{Q_d}{C_{ox}} = V_{FB} + 2V_P + \frac{q x_{dmax} N_A}{C_{ox}}$$



in short devices, small statistical variations in gate length give rise to large statistical variations of V_T (problem of reproducibility in integrated circuits)

Remarks

- The short channel effect can be reduced by using shallower junctions and higher substrate doping \Rightarrow to reduce the extension of the source & drain depletion regions in the channel.
- if the gate length is very small and V_{DS} is high enough, the source and drain depletion region can touch one another $V_{DS} < 0$. \Rightarrow The potential in the channel region is no longer controlled by the gate and a large current can flow from source to drain.
 \Rightarrow this is called "punchthrough"